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Thursday, December 10, 2020

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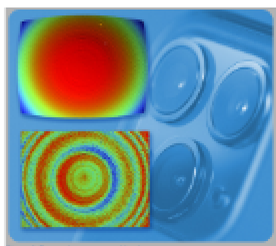
WHITE PAPERS & APPLICATION NOTES

USI Universal Adaptive Profiling Measurement Mode for Superior Surface Texture Characterization



Innovation with Integrity

Optical Metrology

USI Universal Adaptive Profiling Measurement Mode for Superior Surface Texture Characterization

Bruker has recently released the Universal Scanning Interferometry (USI) measurement mode to enable universal measurement results on wide-ranging surfaces for ContourX white light interferometry (WLI) profilometers. USI provides fully automated, self-sensing surface texture optimized signal processing while delivering the most accurate and realistic computation of the surface topography being analyzed.

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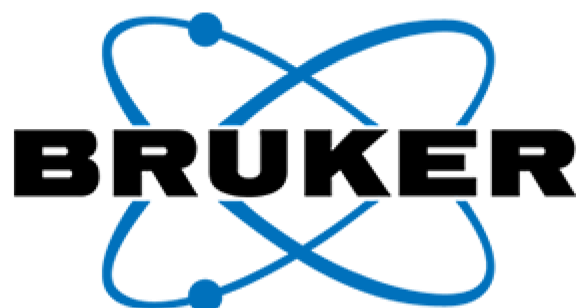

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